



1. Grow field oxide



2. Etch oxide for pMOSFET



3. Diffuse n-well



4. Etch oxide for nMOSFET



5. Grow gate oxide



6. Deposit polysilicon



7. Etch polysilicon and oxide



8. Implant sources and drains



9. Grow nitride



10. Etch nitride



11. Deposit metal



12. Etch metal



p-type
substrate



oxide



n-well



polysilicon



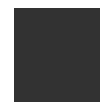
n+



p+



nitride



metal